

<b>Notice of References Cited</b>	Application/Control No. 10/525,443	Applicant(s)/Patent Under Reexamination TAKAHASHI ET AL.	
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**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
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**FOREIGN PATENT DOCUMENTS**

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**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Takahashi et al, Preparation of pyrite thin films by atmospheric pressure chemical vapor deposition using FeCl3 and CH3CSNH2, J. Mater. Chem., 2000, 10, p. 2346-2348.
	V	Schleich et al, Iron pyrite and iron marcasite thin films prepared by low pressure chemical vapor deposition, Journal of Crystal Growth, Vol. 112, Issue 4, July 1991, Abstract (2 pages).
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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